

first reflective portion extending in the first direction, a second reflective portion parallel to the first reflective portion, and a first mark portion having a plurality of fiducial marks;

 a first position detector that detects a position of the first movable stage cooperating with the first reflective portion;

 a first mark detector that detects the plurality of fiducial marks when the first position detector detects the position of the first movable stage;

 a second position detector that detects a position of the first movable stage cooperating with the second reflective portion;

 a second mark detector that detects the plurality of fiducial marks when the second position detector detects the position of the first movable stage;

 a projection system that projects a pattern onto the first substrate; and

 a controller that communicates with the first position detector, the second position detector, the first mark detector, and the second mark detector to correlate the first reflective portion with the second reflective portion.

33 24. (Amended) A method for making a stage assembly that moves a device, the method comprising the steps of:

 providing a device table for retaining the device;

 connecting a stage mover assembly to the device table, the stage mover assembly moving the device table;

 providing a measurement system that monitors a position of the device table, the measurement system including a first X mirror, a second X mirror, and a Y mirror that are secured to the device table;

 providing a first fiducial mark and a second fiducial mark for the device table; and

providing a controller that determines the position of the first X mirror relative to the second X mirror using the first fiducial mark and the second fiducial mark.

25. (Amended) The method of claim 24 wherein the controller determines the position by measuring (i) the position of the first fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror, and (ii) the position of the second fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror.

B3
26. (Amended) The method of claim 25 wherein the controller determines the position of the first X mirror relative to the second X mirror by utilizing the measured position of the first fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror, and the measured position of the second fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror.

27. (Amended) The method of claim 24 further comprising providing a third fiducial mark for the device table, the third fiducial mark also being used to determine the position of the first X mirror relative to the second X mirror.

28. (Amended) The method of claim 27 wherein the controller determines the position by measuring (i) the position of the first fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror, (ii) the position of the second fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror, and (iii) the position of the third fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror.

29. (Amended) The method of claim 28 wherein the controller determines the position of the first X mirror relative to the second X mirror by utilizing the measured position of the first fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror, the measured position of the second fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror, and the measured position of the third fiducial mark relative to the first X mirror, the second X mirror, and the Y mirror.

32. (Amended) A method of making a device comprising the steps of:
providing a first movable stage that moves in a first direction and a second direction different from the first direction, the first movable stage holding the device and having a first reflective portion extending in the first direction, a second reflective portion parallel to the first reflective portion, and a first mark portion having a plurality of fiducial marks;

B4

providing a first position detector that detects a position of the first movable stage cooperating with the first reflective portion;

providing a first mark detector that detects the plurality of fiducial marks when the first position detector detects the position of the first movable stage;

providing a second position detector that detects a position of the first movable stage cooperating with the second reflective portion;

providing a second mark detector that detects the plurality of fiducial marks when the second position detector detects the position of the first movable stage;

providing a controller that communicates with the first position detector, the second position detector, the first mark detector, and the second mark detector to correlate the first reflective portion with the second reflective portion;

exposing a pattern onto the device by a projection system; and

assembling the device on which the pattern has been formed.

[Please add new claims 33-44 as follows:]

--33. (New) The exposure apparatus of claim 13, wherein the first position detector and the second position detector comprise an interferometer system.--

--34. (New) The exposure apparatus of claim 13, wherein the first movable stage has a third reflective portion extending in the second direction.--

--35. (New) The exposure apparatus of claim 13, wherein the first movable stage is a cantilevered stage.--

--36. (New) The exposure apparatus of claim 13, wherein each of the plurality of fiducial marks of the first mark portion comprises a two dimensional mark.--

B4

--37. (New) The exposure apparatus of claim 13, further comprising a second movable stage that moves in the first direction and the second direction, the second movable stage holding a second substrate and having a fourth reflective portion extending in the first direction, a fifth reflective portion parallel to the fourth reflective portion, and a second mark portion having a plurality of fiducial marks.--

--38. (New) The exposure apparatus of claim 37, wherein the controller correlates the fourth reflective portion with the fifth reflective portion.--

--39. (New) The exposure apparatus of claim 37, further comprising a replacer that replaces the first and second movable stages with respect to the first and second position detectors.--

--40. (New) The exposure apparatus of claim 39, wherein the first mark detector detects the second mark portion when the first position detector detects a position of the second movable stage cooperating with the fourth reflective portion.--

--41. (New) The exposure apparatus of claim 39, wherein the second mark detector detects the second mark portion when the second position detector detects a position of the second movable stage cooperating with the fifth reflective portion.--

--42. (New) The exposure apparatus of claim 37, wherein the second movable stage has a sixth reflective portion extending in the second direction.--

--43. (New) The exposure apparatus of claim 37, wherein the second movable stage is a cantilevered stage.--